

**Development of  
Radiation Hard Sensors for  
Very High Luminosity Colliders  
- CERN-RD50 project -**

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**On behalf of CERN RD50 Collaboration**

**<http://www.cern.ch/rd50>**

# Outline

- **Motivation and Introduction to RD50**
- **Radiation Damage**
  - **Microscopic defects (changes in bulk material)**
  - **Macroscopic damage (changes in detector properties)**
- **RD50 - Approaches to obtain radiation hard sensors**
  - **Material Engineering**
  - **Device Engineering**
- **RD50 – future work plan**
- **Summary**

## **RD50 – A very young collaboration!**

**11/2001 – Workshop on rad-hard devices**

**02/2002 - R&D Proposal**

**06/2002 - Approved as CERN-RD50**

**10/2002 - 1<sup>st</sup> RD50 Workshop**

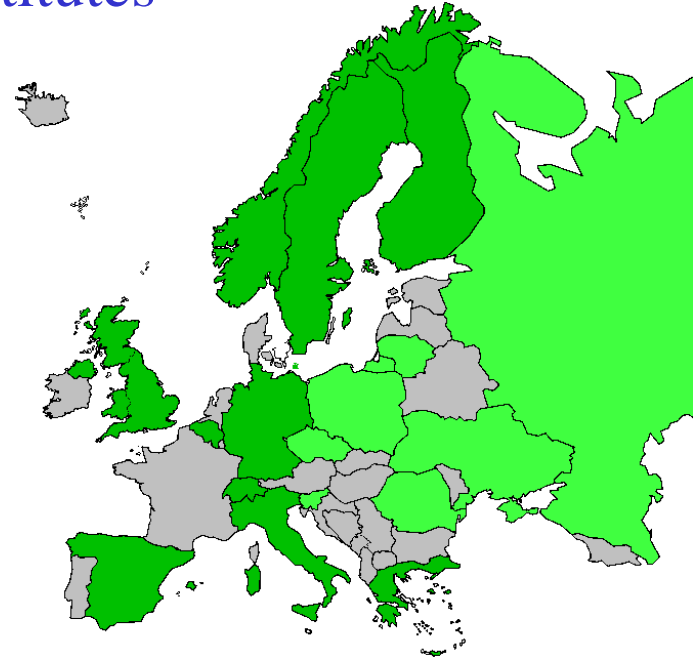
**now: startup of specialized working groups**

# RD50 - Development of Radiation Hard Semiconductor Devices for High Luminosity Colliders

274 Members from 52 Institutes

## 45 European and Asian institutes (34 west, 11 east)

**Belgium** (Louvain), **Czech Republic** (Prague (2x)),  
**Finland** (Helsinki (2x), Oulu), **Germany** (Berlin, Dortmund, Erfurt,  
Halle, Hamburg, Karlsruhe), **Greece** (Athens), **Italy** (Bari,  
Florence, Milano, Modena, Padova, Perugia, Pisa, Trento, Trieste),  
**Lithuania** (Vilnius), **Norway** (Oslo (2x)), **Poland** (Warsaw),  
**Romania** (Bucharest (2x)), **Russia** (Moscow (2x), St.Petersburg),  
**Slovenia** (Ljubljana), **Spain** (Barcelona, Valencia), **Sweden** (Lund)  
**Switzerland** (CERN, PSI), **Ukraine** (Kiev), **United Kingdom**  
(Exeter, Glasgow, Lancaster, Liverpool, London, Sheffield,  
University of Surrey)



## 6 North-American institutes

**Canada** (Montreal), **USA** (Fermilab, Purdue University, Rutgers  
University, Syracuse University, BNL)



## 1 Middle East institute

**Israel** (Tel Aviv)

Detailed member list: <http://cern.ch/rd50>

# Motivation to form a new R&D Collaboration

- **LHC upgrade (“Super-LHC” ... later than 2010)**

$$\text{LHC: } L = 10^{34} \text{cm}^{-2}\text{s}^{-1} \xrightarrow{10 \text{ years}} \begin{array}{l} f(\text{R}=4\text{cm}) \sim 3 \cdot 10^{15} \text{cm}^{-2} \\ f(\text{R}=75\text{cm}) \sim 3 \cdot 10^{13} \text{cm}^{-2} \end{array}$$

⇒ Technology available ⇒ However, serious radiation damage!

$$\text{S-LHC: } L = 10^{35} \text{cm}^{-2}\text{s}^{-1} \xrightarrow{5 \text{ years}} f(\text{R}=4\text{cm}) \sim 1.6 \cdot 10^{16} \text{cm}^{-2}$$

⇒ Focused and coordinated R&D mandatory

⇒ develop radiation hard and cost-effective detectors

- **LHC experiments (...starting 2007)**

Radiation hardness studies also beneficial before a luminosity upgrade.

⇒ Radiation hard technologies now adopted have not been completely characterized: Oxygen-enriched Si in ATLAS/CMS pixels

- **Linear collider experiments**

Deep understanding of radiation damage will be fruitful for linear collider experiments where high doses of  $e$ ,  $\gamma$  will play a significant role.

# RD50 - Scientific objectives and strategies

## Main Objective:

To develop radiation hard semiconductor detectors that can operate beyond the limits of present devices. These devices should withstand fast hadron fluences of the order of  $10^{16}$  cm<sup>-2</sup>, as expected for example for a recently discussed luminosity upgrade of the LHC to  $10^{35}$  cm<sup>-2</sup>s<sup>-1</sup>.

## Three R&D strategies:

### ◆ Material engineering

- Defect engineering of silicon (oxygenation, dimers, ...)
- New detector materials (SiC, ...)

### ◆ Device engineering

- Improvement of present planar detectors  
(3D detectors, thin detectors, cost effective detectors,...)

### ◆ Variation of detector operational conditions

- Low temperature operation
- Forward bias operation

} **RD50**  
Center of gravity

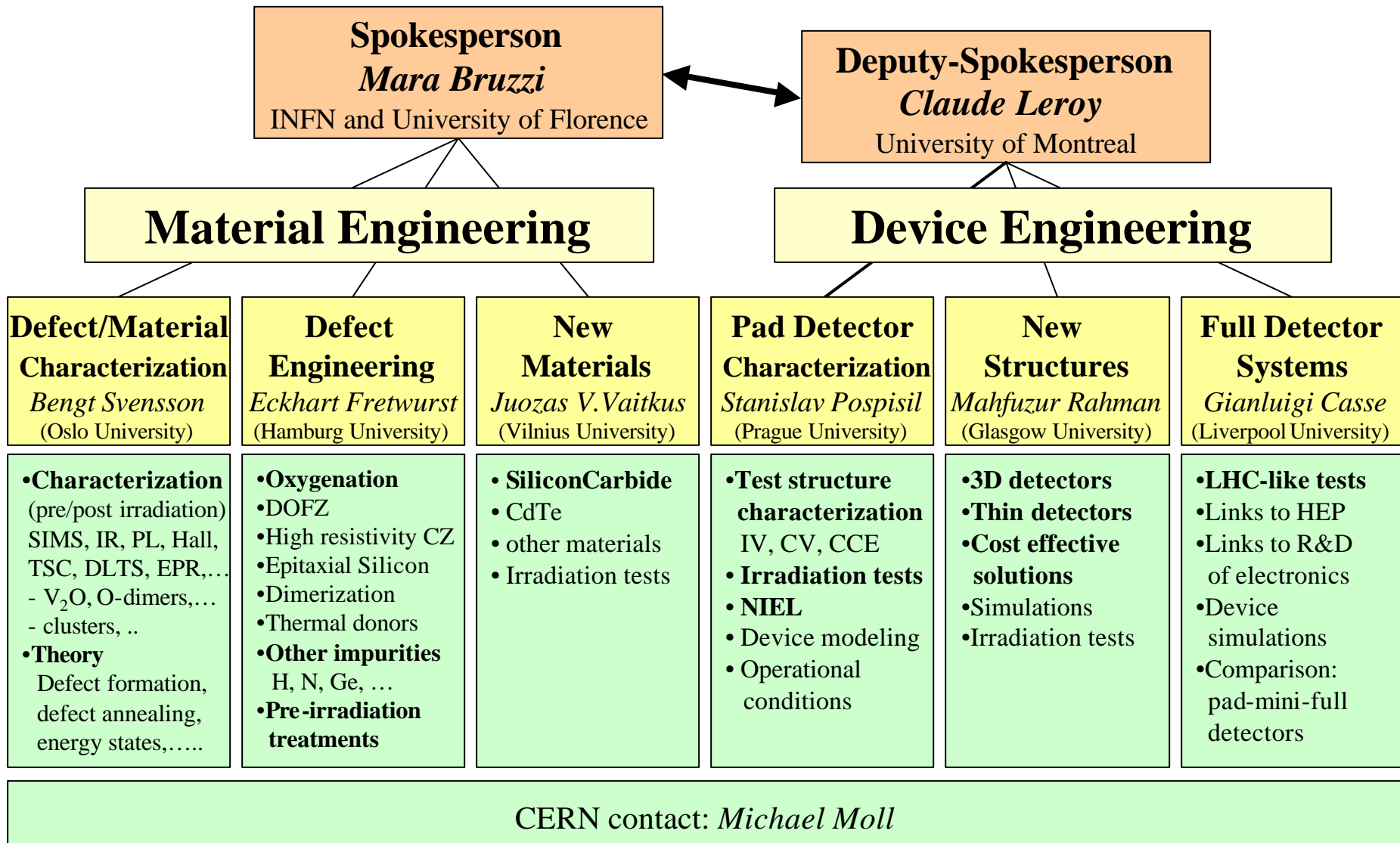
## Further key tasks:

### ◆ Basic studies

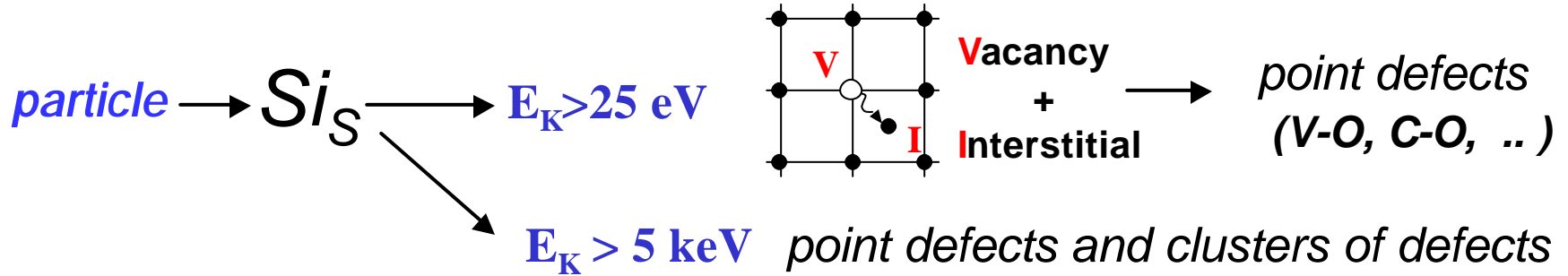
### ◆ Defect modeling and device simulation

# Scientific Organization of RD50

*RD50 - Development of Radiation Hard Semiconductor Devices for High Luminosity Colliders*



# Radiation Damage – Microscopic Effects



## ◆ $^{60}\text{Co}$ -gammas

- Compton Electrons with max.  $E_g \gg 1 \text{ MeV}$  (no cluster production)

## ◆ Electrons

- $E_e > 255 \text{ keV}$  for displacement
- $E_e > 8 \text{ MeV}$  for cluster

## ◆ Neutrons (elastic scattering)

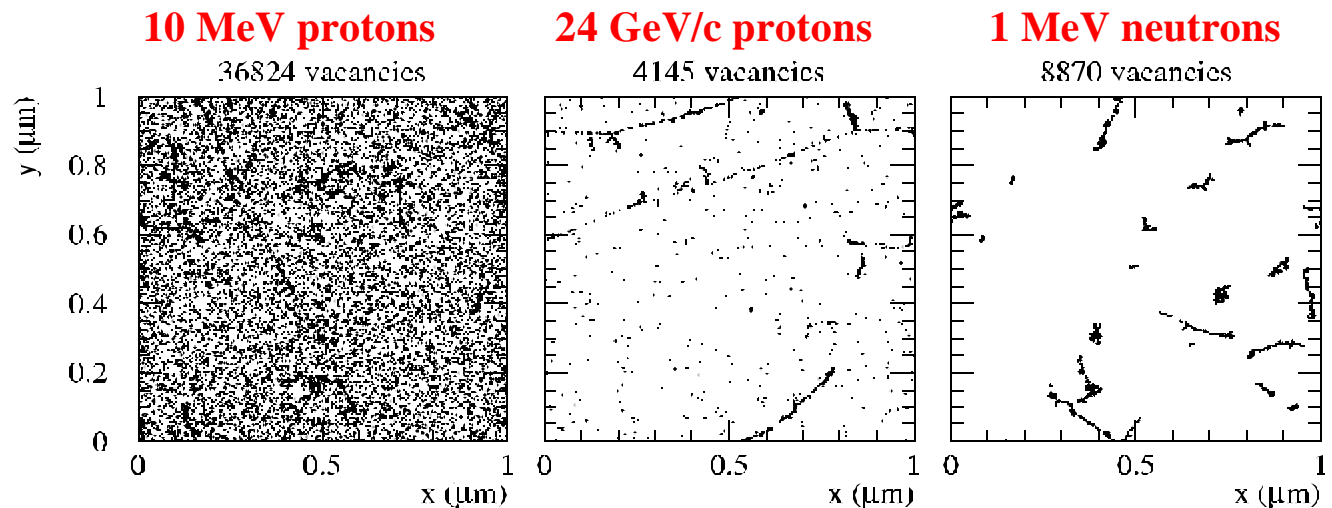
- $E_n > 185 \text{ eV}$  for displacement
- $E_n > 35 \text{ keV}$  for cluster

More point defects  $\leftarrow$

$\rightarrow$  More clusters

Initial distribution of vacancies in  $(1\text{mm})^3$  after  $10^{14}$  particles/cm<sup>2</sup>

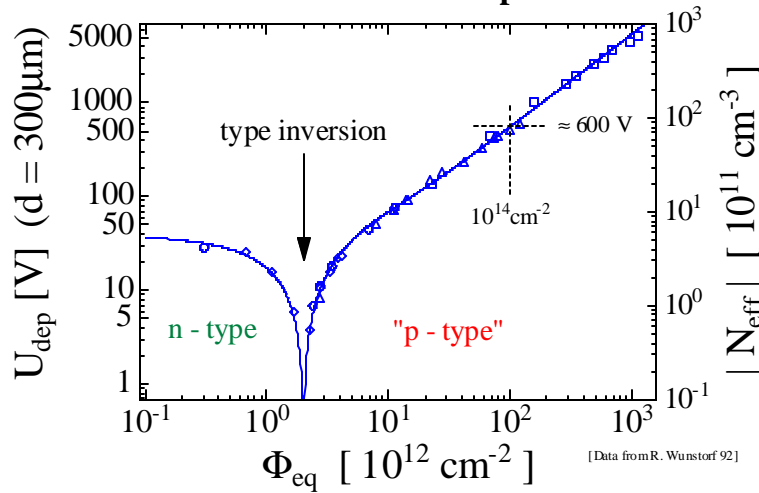
[Mika Huhtinen ROSE TN/2001-02]



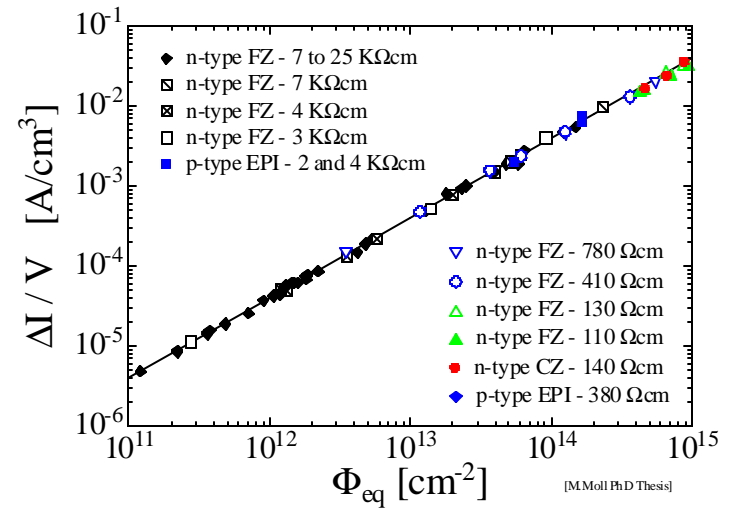
# Radiation Damage – 3 Macroscopic Effects

Irradiation

## 1. Change of $V_{dep}$ ( $N_{eff}$ )

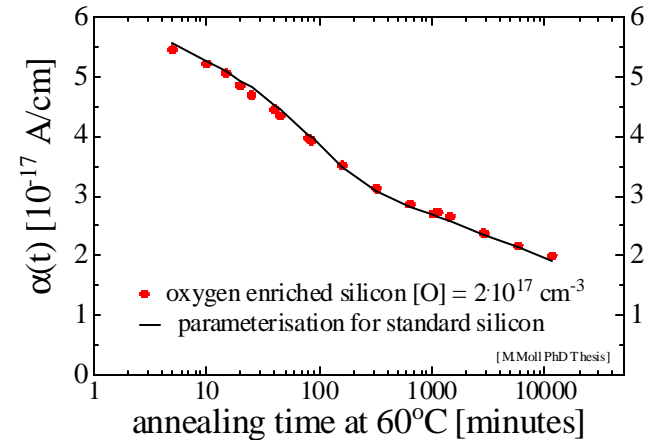
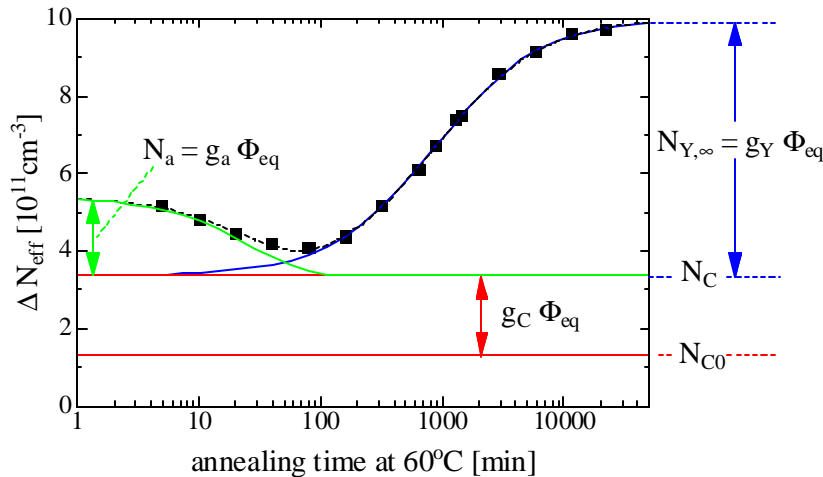


## 2. Increase of leakage current



Annealing

(e.g. at 60°C)



**Gamma irradiation: type inversion and increase of leakage current, but: no annealing !**

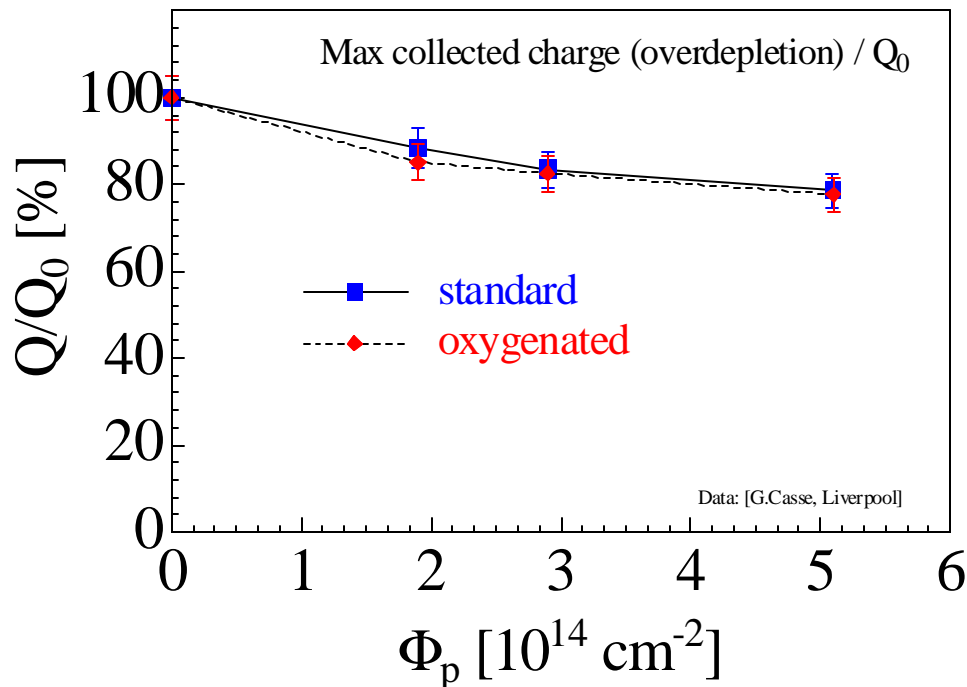


### 3. Deterioration of the charge collection efficiency

#### ◆ Two mechanisms reduce collectable charge:

- Trapping (electrons and holes)
- Underdepletion (detector design and geometry)

#### ATLAS microstrip + RO electronics



- ◆ Oxygenation has no influence on trapping.
- ◆ After  $5 \cdot 10^{14} \text{ p/cm}^2$  (24 GeV/c)
  - 80% of charge collected (25ns)
  - overdepletion needed !

More details in later talk:  
“Charge collection in silicon”  
Gianluigi Casse, Liverpool

Data: Gianluigi Casse; 1<sup>st</sup> Workshop on Radiation Hard Semiconductor Devices for High Luminosity Colliders; CERN; 28-30 November 2002

# Defect Engineering of Silicon

- ◆ Influence the defect kinetics by incorporation of impurities

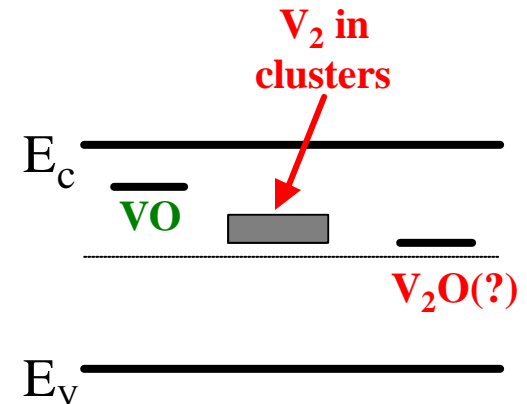
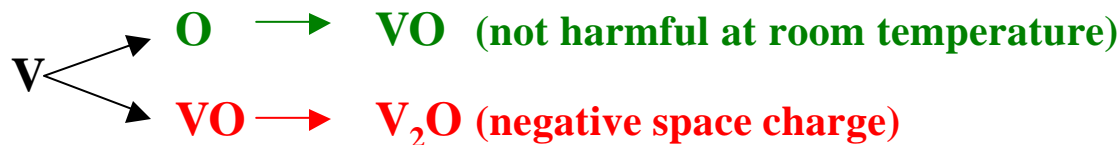
- ◆ Best example: Oxygen

**Idea:** Incorporate Oxygen to getter radiation-induced vacancies

↳ prevent formation of Di-vacancy ( $V_2$ ) related deep acceptor levels

**Observation:** Higher oxygen content ↳ less negative space charge  
(less charged acceptors)

- ◆ One possible mechanism:  $V_2O$  is a deep acceptor



- Experimental evidence for  $V_2O$ ? Yes!

- Acceptor at  $E_c - 0.545 \text{ eV}$  [I.Pintilie: 1<sup>st</sup> RD50 Workshop, APL 81(2002)165]

- Double-acceptor at  $E_c - 0.43 \text{ eV} (-/0)$  and  $E_c - 0.23 \text{ eV} (--/-)$

[E.Monakhov 1<sup>st</sup> RD50 Workshop, PRB 65(2002)233207]

# Oxygen enriched silicon

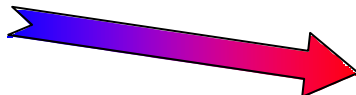
- DOFZ (Diffusion Oxygenated Float Zone Silicon)**

- 1982 First oxygen diffusion tests on FZ [Brotherton et al. J.Appl.Phys.,Vol.53, No.8.,5720]
- 1995 First tests on detector grade silicon [Z.Li et al. IEEE TNS Vol.42,No.4,219]
- 1999 Introduced to the HEP community by RD48 (ROSE)**

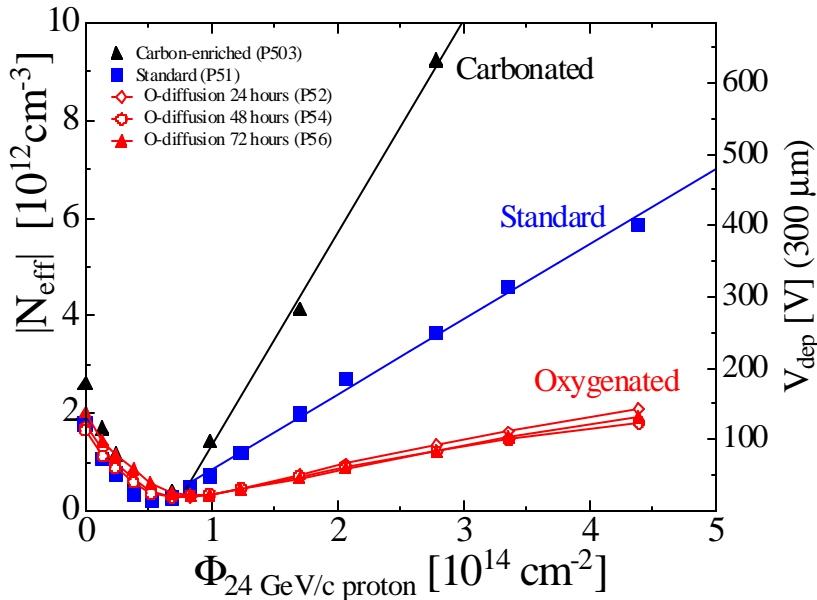


<http://cern.ch/rd48>

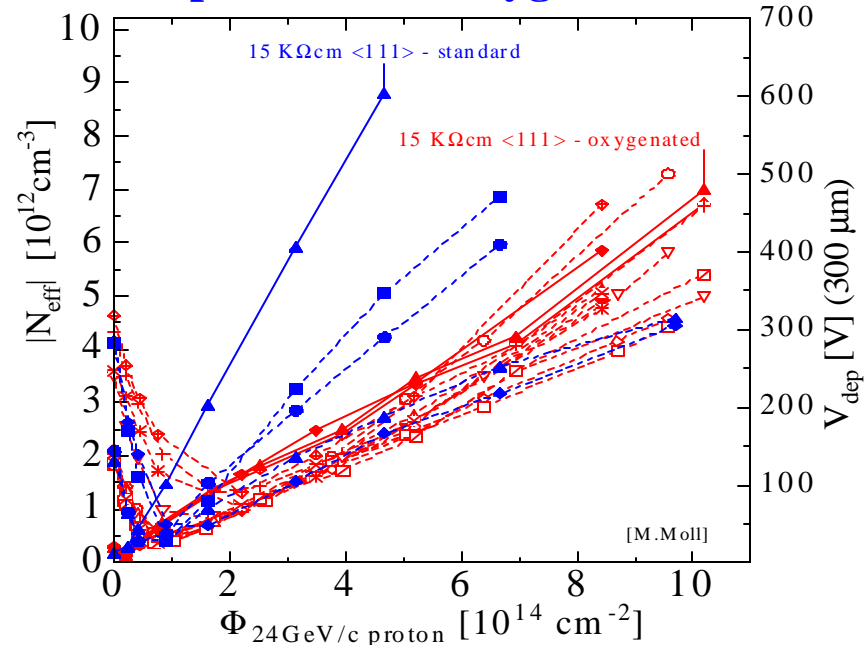
First tests show clear advantage of oxygenation



Later systematic tests reveal strong variations with no clear dependence on oxygen content

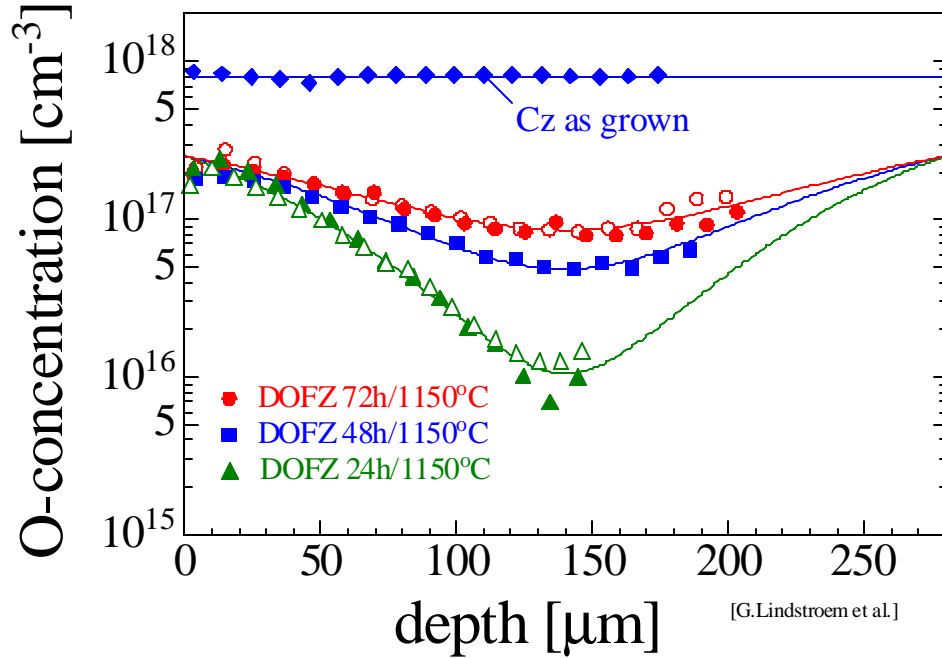


[RD48-NIMA 465(2001) 60]

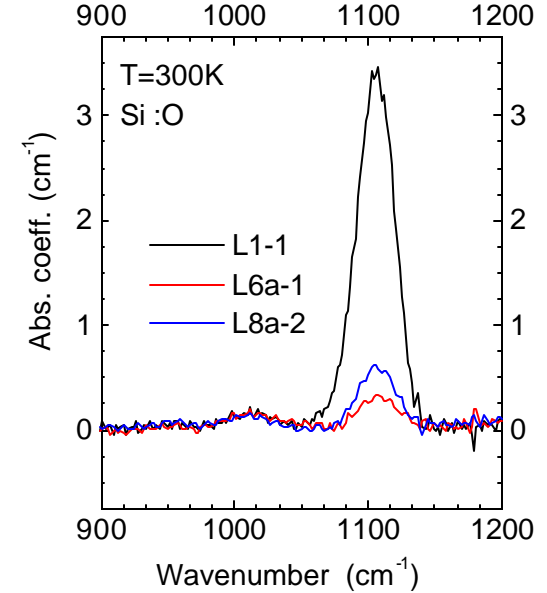


# Characterization of Oxygen concentration in DOFZ

SIMS – [O] depth profile



IR-absorption: average [O]



Sample	CZ	DOFZ 24h/1150C	DOFZ 48h/1150C	DOFZ 72h/1150C
SIMS [O/cm <sup>3</sup> ]	8.1e17	5.7e16	9.9e16	1.2e17
IR [O/cm <sup>3</sup> ]	8.5e17	6.8e16	1.0e17	1.4e17

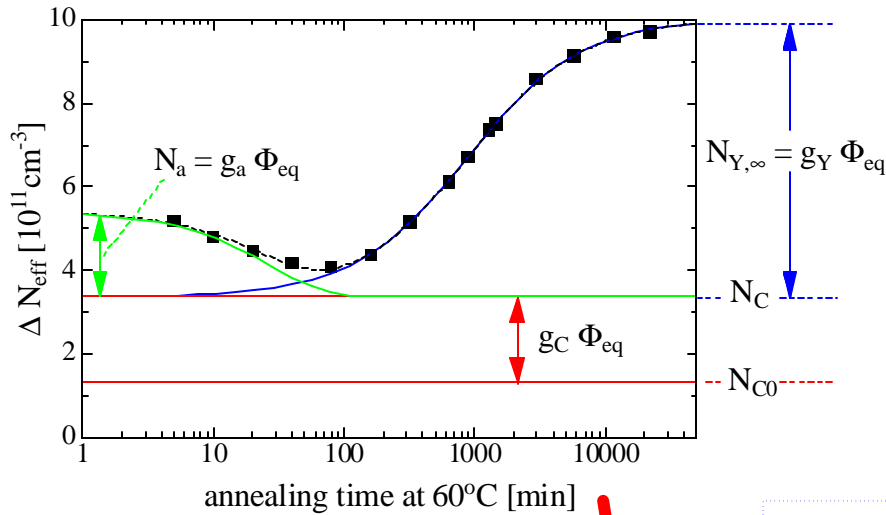
- **Average:  $[O]_{IR}/[O]_{SIMS} = 1.1 \pm 10\%$**
- ⇒ **Oxygen in DOFZ is mono-atomic (no clustering)**

Details: [G.Lindstroem et al. 1<sup>st</sup> RD50-Workshop]

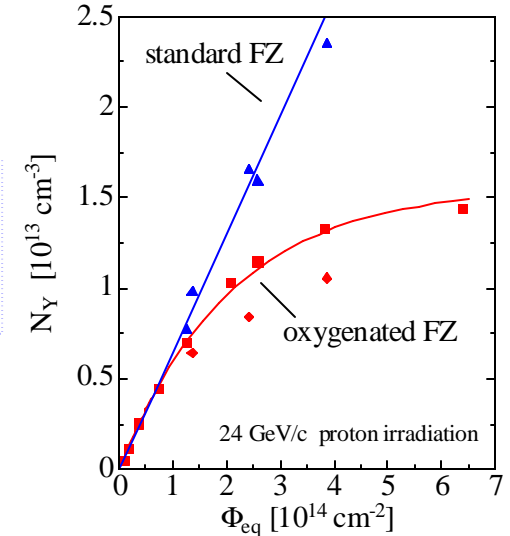
# Annealing after 24 GeV/c proton irradiation

$$DN_{\text{eff}}(F_{\text{eq}}, t) = N_a(F_{\text{eq}}, t) + N_C(F_{\text{eq}}, t) + N_Y(F_{\text{eq}}, t)$$

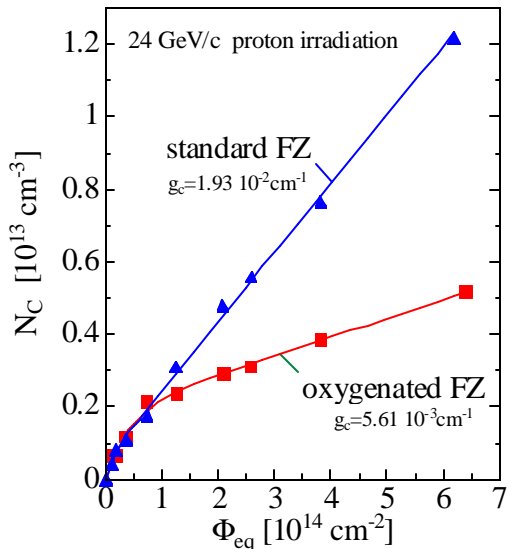
= **beneficial annealing** + **stable damage** + **reverse annealing**



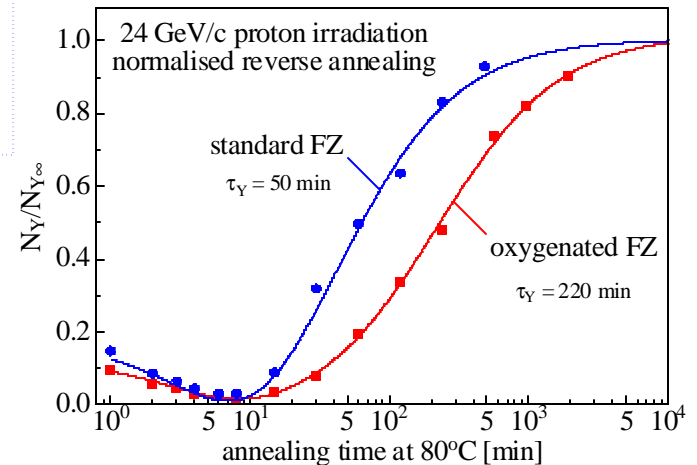
Saturation of reverse annealing



delayed reverse annealing

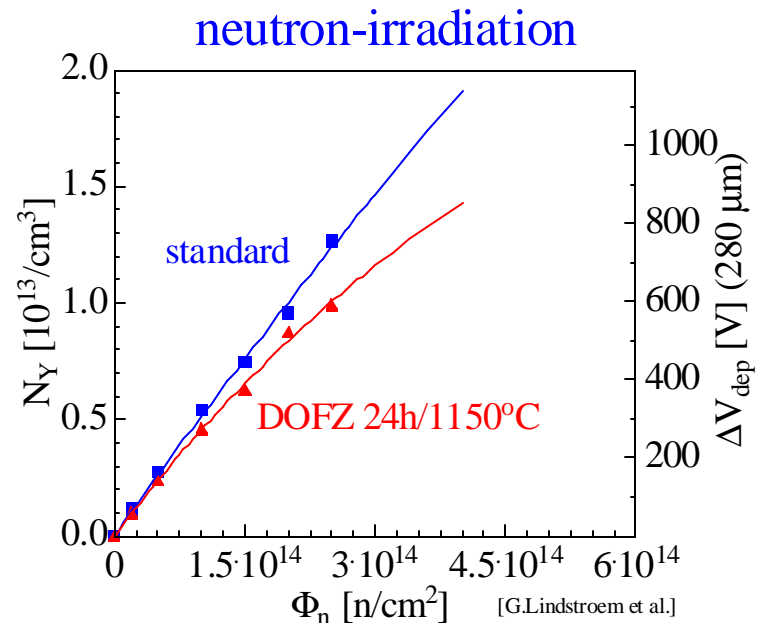
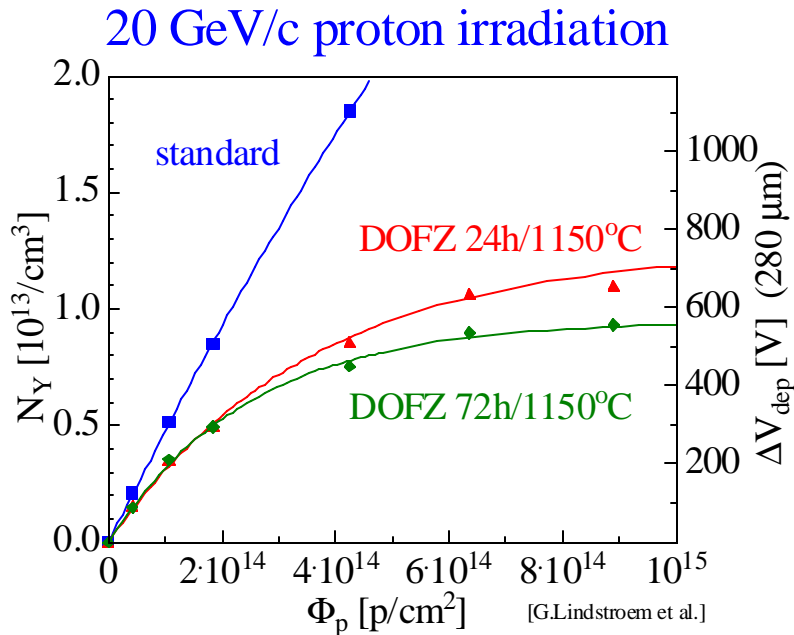
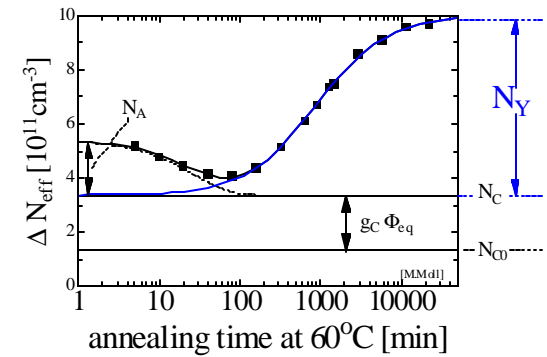


Stable damage reduced by a factor of 3



# How much [O] is enough?

- ◆ Reverse annealing amplitude  $N_Y$  after proton and neutron irradiation

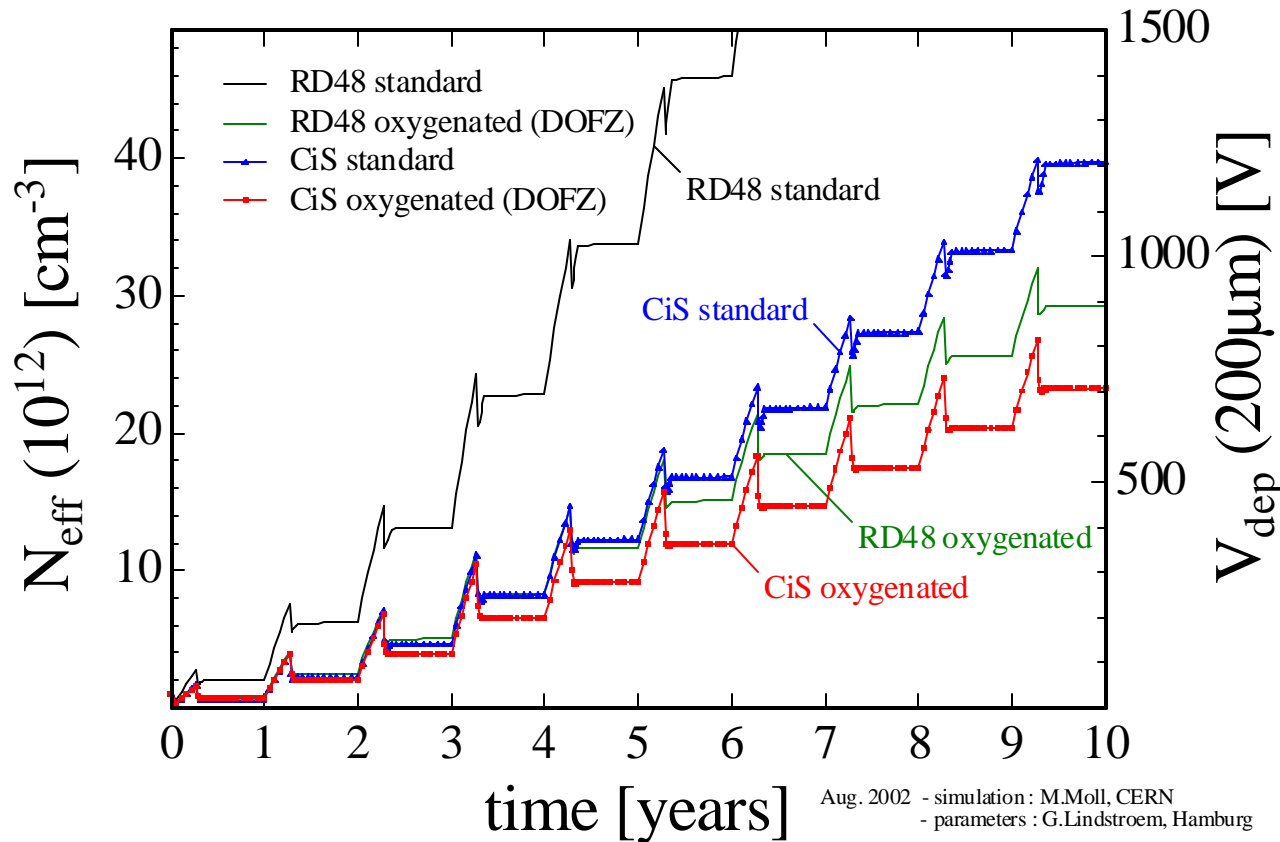


- ◆ Saturation of reverse annealing for protons and neutrons
- ◆ Higher beneficial effect for protons
- ◆ No big difference between 24h and 72h oxidation at 1150°C

Details: [G.Lindstroem et al. 1<sup>st</sup> RD50-Workshop]

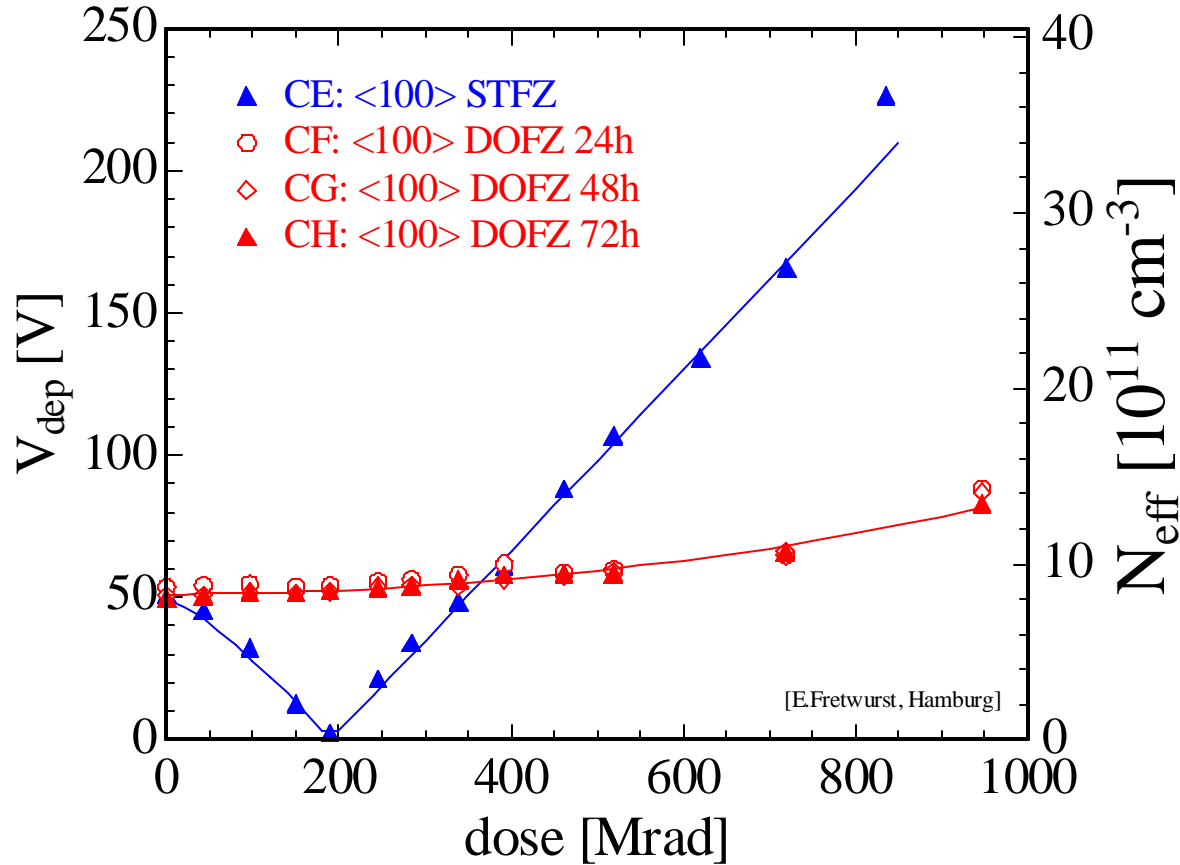
# Updated Damage Projection - ATLAS Pixel B-layer

- ◆ **Radiation level:**
  - $F_{eq}(\text{year}) = 3.5 \cdot 10^{14} \text{ cm}^{-2}$  (full luminosity)
  - $> 85\%$  charged hadrons
- ◆ **LHC-scenario:**
  - 1 year = 100 days beam (-7°C)
  - 30 days maintenance (20°C)
  - 235 days no beam (-7°C)



- ◆ **New:**
  - **Std. Silicon:** rad.harder than predicted by RD48
  - **DOFZ:** reverse annealing delayed and saturating with high fluences

# DOFZ : Spectacular Improvement of g-irradiation tolerance



[E.Fretwurst et al. 1<sup>st</sup> RD50 Workshop]

See also:

- Z.Li et al. [NIMA461(2001)126]

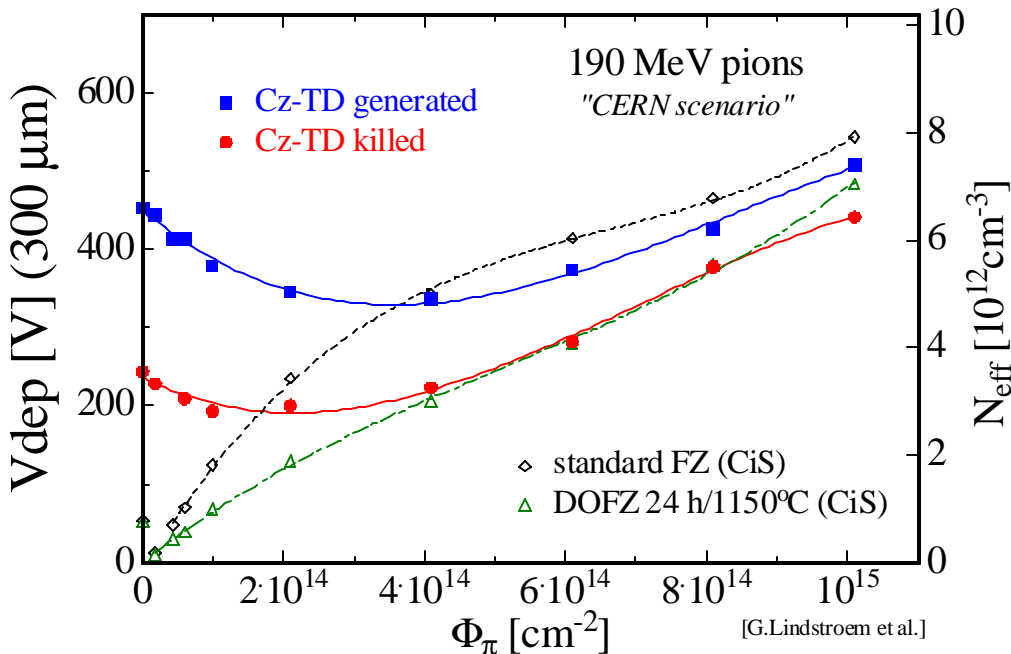
- Z.Li et al. [1<sup>st</sup> RD50 Workshop]

- ◆ **No type inversion for oxygen enriched silicon!**
- ◆ **Slight increase of positive space charge**  
(due to Thermal Donor generation?)



# Material Engineering: Czochralski silicon (CZ)

- ♦ **Very high Oxygen content  $10^{17}$ - $10^{18}\text{cm}^{-3}$**  (Grown in quartz ( $\text{SiO}_2$ )crucible)
- ♦ **High resistivity ( $>1\text{KWcm}$ ) available only recently** (Magnetic CZ technology)
- ♦ **CZ wafers cheaper than FZ** (RF-IC industry got interested)



## ♦ Irradiation of test-structures:

- **Only small change in  $V_{\text{dep}}$**   
up to  $1 \cdot 10^{15} \text{ p/cm}^2$
- **No type inversion**
- **Leakage current and charge trapping**  
as for FZ silicon
- **Very high oxygen content:**  
**Beware of thermal donors !**

Details: [G.Lindstroem, 1<sup>st</sup> RD50 Workshop]  
 [Z.Li, 1<sup>st</sup> RD50 Workshop]

## ♦ First full size detectors produced:

MCZ, 900  $\Omega\text{cm}$ , 32.5  $\text{cm}^2$ , strip 10 $\mu\text{m}$ , pitch 50 $\mu\text{m}$

- **Electrical performance:** 3 $\mu\text{A}$ @900V
- **Test beam:** Signal/Noise  $\approx 10$  ; Efficiency  $\geq 95\%$  ; Resolution of 10 $\mu\text{m}$
- **Radiation tests:** under way

Details: [E.Tuominen, 1<sup>st</sup> RD50 Workshop]

# Defect Engineering: Oxygen Dimers in Silicon

## ◆ Idea: Transform Oxygen into Oxygen dimers ( $O_2$ )

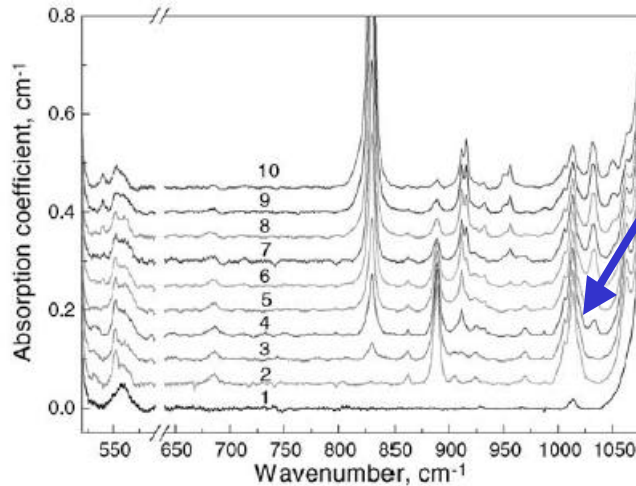
Standard Si :  $V+O \rightarrow VO$ ;  $V+VO \rightarrow V_2O$   $\rightarrow$  deep acceptor (neg. charged)

Dimered Si :  $V+O_2 \rightarrow VO_2$ ;  $V+VO_2 \rightarrow V_2O_2$   $\rightarrow$  Simulations: deep acceptor (but shallower than  $V_2O$ )  
 $\rightarrow$  neutral in SCR ?

## ◆ How to produce silicon containing dimers ?

- $Co^{60}$ - $\gamma$  or electron irradiation at  $350^\circ C$   
 $V+O \rightarrow VO$ ;  $VO+O \rightarrow VO_2$ ;  $I+VO_2 \rightarrow O_2$

## ◆ Does it work ?



- **2001** – L.Lindstroem et al.: IR measurements show dimer line after  $350^\circ C$  electron – irradiation of CZ silicon. [Lindstr.om et al. PhysicaB 308 (2001) 284]

- **2002** – S.Watts et al.: First test on FZ detectors performed. No clear evidence for dimers. [Watts et al NIMA485 (2002) 153]

- **2003** - Systematic tests under way (RD50 - Dimer Task Force)

Fig. 1. Room temperature absorption spectra for C-lean n-Cz-Si ( $\rho = 50 \Omega cm$ ): (1) as-grown; (2) after electron irradiation at  $350^\circ C$ ,  $F = 8 \times 10^{17} cm^{-2}$ ; (3-10) after RT irradiation.  $F(cm^{-2})$ : (3)  $1 \times 10^{16}$ , (4)  $5 \times 10^{16}$ , (5)  $10^{17}$ , (6)  $2 \times 10^{17}$ , (7)  $4 \times 10^{17}$ , (8)  $7 \times 10^{17}$ , (9)  $1.1 \times 10^{18}$ , (10)  $6 \times 10^{18}$ .

# Epitaxial SiC

“A material between Silicon and Diamond”

Property	Diamond	4H SiC	Si
$E_g$ [eV]	5.5	3.3	1.12
$E_{\text{breakdown}}$ [V/cm]	$10^7$	$4 \cdot 10^6$	$3 \cdot 10^5$
$\mu_e$ [ $\text{cm}^2/\text{Vs}$ ]	1800	800	1450
$\mu_h$ [ $\text{cm}^2/\text{Vs}$ ]	1200	115	450
$v_{\text{sat}}$ [cm/s]	$2.2 \cdot 10^7$	$2 \cdot 10^7$	$0.8 \cdot 10^7$
Z	6	14/6	14
$\epsilon_r$	5.7	9.7	11.9
e-h energy [eV]	13	8.4	3.6
$\tau_h$ [s]	$10^{-9}$	$5 \cdot 10^{-7}$	$2.5 \cdot 10^{-3}$
Wigner En.[eV]	43	25	13-20

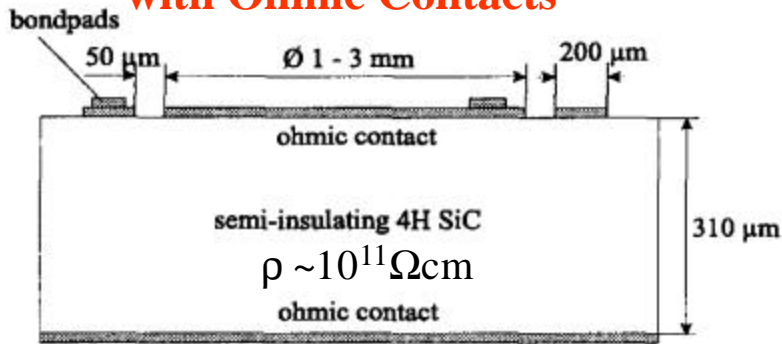
♦ Wide bandgap (3.3eV)  
 ⇒ lower leakage current than silicon

♦ Signal:  
 Diamond 36 e/mm  
 SiC 51 e/mm  
 Si 89 e/mm  
 ⇒ more charge than diamond

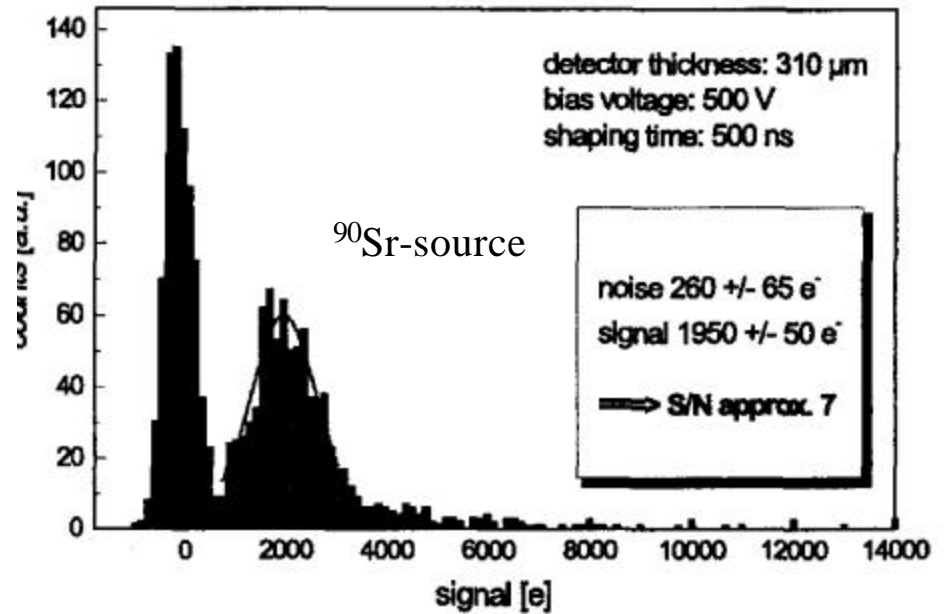
♦ Higher displacement threshold than silicon  
 ⇒ radiation harder than silicon (?)

About Diamond:  
 See later talk “Diamond”  
 by *Mara Bruzzi*

## Semi-insulating 4H-SiC with Ohmic Contacts

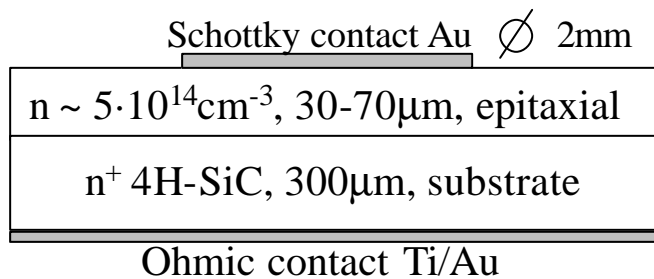


polarization effects due to deep traps/micropipes  
 ® CCE deterioration



Nucl.Phys.B Proc. Suppl.78 (1999), 516

## Schottky Barrier Epitaxial SiC



low defect density in epi layer  
 ® negligible polarization effects

**Present status: e.g. CREE (USA)**

- 20-50 μm epitaxial 4H-SiC
- ≈ 9.000\$ - 2" wafer

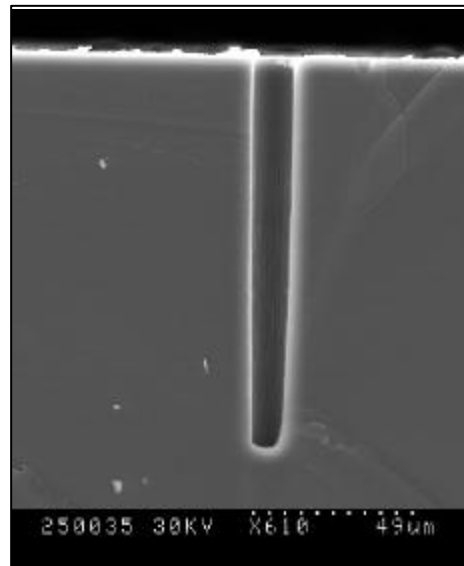
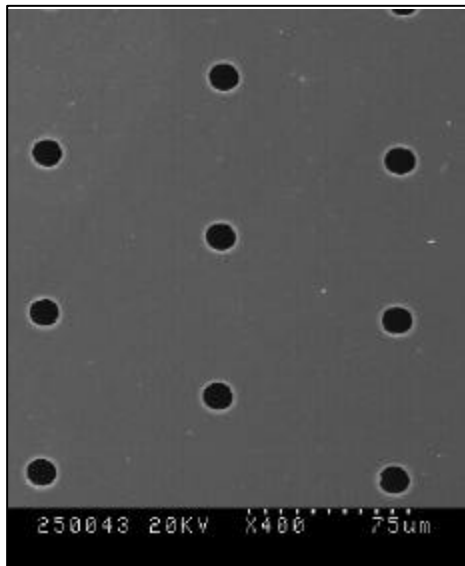
# Device Engineering: 3D detectors

## ◆ Electrodes:

- narrow columns along detector thickness-“3D”
- diameter:  $10\mu\text{m}$  distance:  $50 - 100\mu\text{m}$

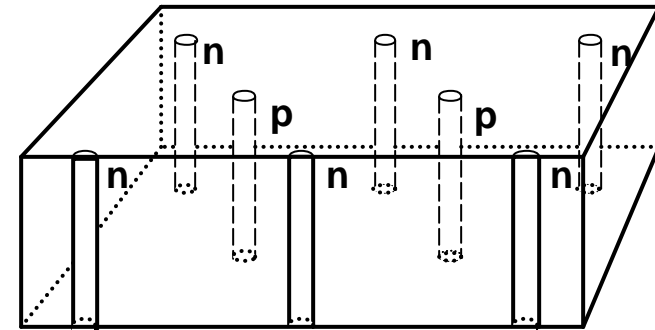
## ◆ Lateral depletion:

- lower depletion voltage needed
- thicker detectors possible
- fast signal



[P. Roy, Glasgow, 1<sup>st</sup> RD50 Workshop]

Present size up to  $\sim 1\text{cm}^2$



## ◆ Hole processing :

- Dry etching
- Laser drilling
- Photo Electro Chemical

## ◆ Electrode material

- Doped Polysilicon (Si)
- Schottky (GaAs)

## ◆ Irradiation tests

- $1 \cdot 10^{15} \text{ p/cm}^2$  (55 MeV, 23 GeV)
- $2 \cdot 10^{14} \text{ p/cm}^2$  (190 MeV)

More details on Friday:  
“Molecular Biology”  
Sherwood Parker, Hawaii

# Device Engineering: thin detectors

## Benefits:

- better tracking precision and momentum resolution
- low operating voltage
- more precise timing
- improved radiation tolerance:

50 $\mu$ m thick, 50 $\Omega$ cm Si detector ( $V_{\text{dep}} = 200\text{V}$ ): type inversion after  $10^{15} \text{ cm}^{-2}$

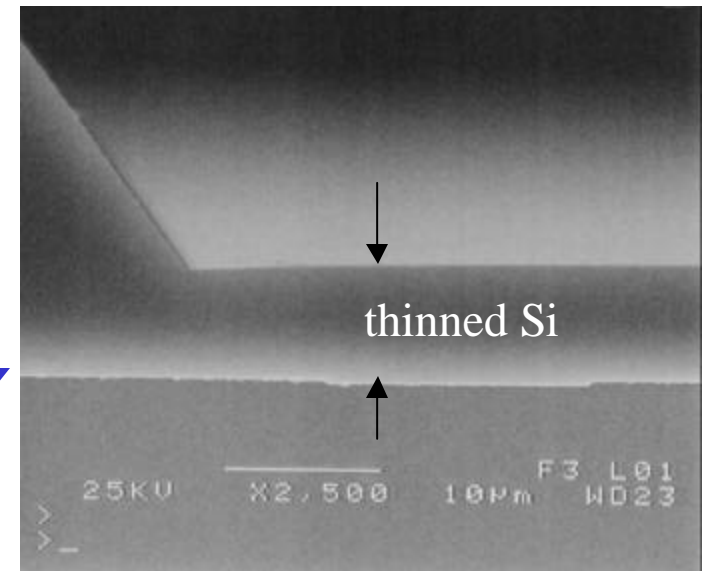
## Drawbacks:

- mip signal  $\sim 3500\text{e-h}$  pairs
- relatively broad Landau distribution at higher values

## Technical Approach:

- Epitaxial Si device
- Thinning with chemical attacks and micro-machining

Thinning Si by chemical attack (IRST – Trento)



# RD50 – Work plan – What is happening right now?

## All RD50 institutes:

- **Inter-calibration** of microscopic/macrosopic measurement **equipment/procedures**
- **Exchange** of already produced **samples** and on-stock material
- Design of **common masks** for test structures
- Evaluation of **irradiation facilities**, common irradiation runs

## RD50 subgroups already working on:

- DOFZ (influence of process, particle dependence of damage)
- Epitaxial silicon, Hydrogen and Thermal donors in silicon
- High resistivity CZ detector characterization/production
- $V_xO_x$  defect identification and simulation, Oxygen dimer production
- Irradiation of samples up to very high fluences  $> 5 \cdot 10^{15} \text{ cm}^{-2}$ , CV – CCE comparison
- Evaluation of semiconductors other than silicon, production of 4H-SiC wafers
- 3D and thin detectors – optimal processing technique?
- Cross check of detector simulation tools within RD50
- ... much more

# Summary

- ◆ **Future detectors for** - **LHC upgrade** will face fluences up to  $1.6 \cdot 10^{16} \text{cm}^{-2}$   
- **Linear Collider** will face high flux of e-m-radiation
  - ◆ **Newly formed CERN-RD50 collaboration following three strategies:**
    - **Material Engineering**  
Silicon: Oxygenation, CZ, dimers, other impurities, ...  
New Materials: SiC and others
    - **Device Engineering**  
Geometries with short carrier drift length: 3D and thin detectors  
Device modeling, cost effective solutions, n-in-p, n-in-n, ...
    - **Modification of Operational Conditions**  
Forward Bias operation, charge injection, ...
  - ◆ **Different particles cause different displacement damage**
    - Increase of leakage current
    - Change of  $V_{\text{dep}}$ : Increase of negative space charge (not for CZ silicon)
    - Charge loss: Trapping and loss of active volume
- ⇒ **To obtain ultra radiation hard sensors a combination of the above mentioned approaches depending on radiation environment, application and available readout electronics will be best solution.**

**Further information:** <http://cern.ch/rd50/>

e.g.: Proposal and all transparencies of 1<sup>st</sup> RD50 Workshop (CERN, 2-4 Oct 2002)